

#31/F VA -3/20/03

IN THE UNITED STATES PATENT & TRADEMARK OFFICE

IN RE APPLICATION OF

HIROYUKI YANO ET AL

: EXAMINER: DEO, D. V.

RECEIVED

SERIAL NO: 09/531,163

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FILED: MARCH 17, 2000

: GROUP ART UNIT: 1765

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FOR: AQUEOUS DISPERSION,

AQUEOUS DISPERSION FOR CHEMICAL MECHANICAL POLISHING USED FOR MANUFACTURE OF

SEMICONDUCTOR DEVICES,

METHOD FOR MANUFACTURE OF SEMICONDUCTOR DEVICES, AND METHOD FOR FORMATION OF

EMBEDDED WIRING

AMENDMENT AND REQUEST FOR RECONSIDERATION

ASSISTANT COMMISSIONER FOR PATENTS WASHINGTON, D.C. 20231

SIR:

Responsive to the Office Action of November 15, 2002, Applicants respectfully request reconsideration of the above-identified application in view of the following amendment and remarks.

IN THE CLAIMS

Please cancel Claims 44-60.

Please add the following claims: